

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2815 Examiner: Edgardo Ortiz Confirmation No.: 6303

In re PATEN	Γ APPLICATION of:	
Applicant:	Akira TAKAHASHI	)
Serial No.:	10/798,482	)
Filed:	March 12, 2004	) SUBMISSION OF ) FORMAL DRAWINGS
For:	Dry etching method for semiconductor device	) ) )
Docket No.:	OKI 414	) ) July 12, 2005

MAIL STOP AMENDMENT - no fee

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Applicant hereby submits 3 sheets of replacement Formal Drawings (Figs. 1-3(c)).

Respectfully submitted,

July 12, 2005

Date

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